

In the United States Patent and Trademark Office

Applicants: Julia S. Svirchevski et al.

Applicants' Reference: LAM1P109

Application No. 09/336,401 ✓

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Title: POST-PLASMA PROCESSING WAFER
CLEANING METHOD AND SYSTEM

Examiner: Unassigned

Group Art Unit: 1765

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231 on June 15, 2000.

Signed:

Diane Schwanbeck

Separate Letter to the Official Draftsperson

Assistant Commissioner for Patents
Box: Official Draftsperson
Washington, D.C. 20231

Dear Sir:

Applicants hereby attach twelve (12) sheets of formal drawings (Figures 1A, 1B, 1C, 1D, 1E, 2A, 2B, 2C, 2D, 3A, 3B, 3C, 3D, 4, 5, and 6) for the above-referenced patent application. In the event the Draftsperson has any questions concerning the formal drawings, he or she is respectfully requested to contact the undersigned. If any fees are due in connection with the filing of these drawings, then please charge such fees to our Deposit Account No. 50-0805 (Order No. LAM1P109).

Respectfully submitted,
MARTINE PENILLA & KIM, LLP



Peter B. Martine
Reg. No. 32,043

710 Lakeway Drive, Suite 170
Sunnyvale, California 94086
(408) 749-6900

Attorney Docket No. LAM1P109

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